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1 Supplementary Information

2 From 20% Single-Junction Organic Photovoltaic to 26% Perovskite/Organic

3 Tandem Solar Cells: Self-Assembled Hole Transport Molecules Matters

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1 **<u>1. Device fabrication</u>**

2 OSCs device fabrication

The OSC devices were fabricated with the conventional configuration of 3 glass/ITO/SAMs/active layer/C60/BCP/Ag. The patterned ITO-coated glass substrate 4 (15 Ω /sq) was cleaned with detergent and deionized water ultrasonic cleaning 20 min, 5 then continuously cleaned three times with acetone, and isopropanol for 15 min of 6 each step. After that the substrate was dried with a nitrogen gun and then placed in an 7 ultraviolet-ozone cleaning machine for 20 min. This step can further remove the 8 organic residue on the substrate surface and improve the hydrophilicity of the 9 substrate surface. The 4PADCB or 4PADCB+TCB (weight ratio of 1:1) were 10 dissolved in isopropanol (IPA) with a concentration of 0.5 mg/mL and placed into an 11 12 ultrasonic bath for 20 min. The SAM solution (65 μ L for a 1.5 \times 1.5 cm² substrate) 13 was applied directly onto the ITO substrate for 40 s followed by a spin-coating step at 14 3000 rpm for 30 s. The ITO/SAM substrate was then placed onto a hotplate and 15 annealed at 100 °C for 10 min. Finally, the ITO/SAM substrates were transferred 16 inside a dry nitrogen glove box for solar cell fabrication. The PM6, BTP-eC9, Y6 and 17 PC71BM were purchased from organtec.ltd. For the PM6: BTP-eC9 system, the PM6:BTP-eC9 solution was prepared by dissolving blends with a weight ratio of 18 1:1.2 in chloroform (total concentration 15.4 mg/mL) and stirred at room temperature 19 for 2 hours. The active layer was spin-coated on the ITO/SAM substrates at 3500 rpm 20 21 and then annealed 5 min at 80 °C. Finally, C60 (10 nm)/BCP (5 nm)/Ag (100 nm)

1 layers were deposited to complete the device fabrication.

2 Wide-bandgap perovskite single-junction device fabrication

The substrates were then spin-coated with NiO_X (10 mg/mL in deionized water) 3 nanoparticle dispersion. Then, the films were transferred to a nitrogen-filled glovebox 4 and the Me-4PACz (1 mg/mL in IPA) was spin-coated on the substrates at 4,000 rpm 5 and heated at 100°C The 1 6 for 30 s for 10 min. Μ perovskite (Cs_{0.25}FA_{0.75}Pb(Br_{0.5}I_{0.5})₃) precursor solution used contains 129 mg FAI, 65 mg CsI, 7 275 mg PbBr₂, and 115 mg PbI₂, which were dissolved in 1 mL mixed solvent of 8 DMF:DMSO (v/v = 4:1). Then, the precursor solution was shaken overnight at 60°C. 9 10 For the spin-coating process, the substrate was spun at 4,000 rpm for 45 s with an acceleration of 4,000 rpm/s, and 200 mL of MeAc was slowly dropped at 15 s before 11 the spin-coating ended. The perovskite 12

13 films were then annealed at 100°C for 15 min. Then, the C60 (10 nm)/BCP (5 nm)/Ag

14 (100 nm) layers were deposited to complete the device fabrication.

15 Perovskite-organic tandem device fabrication

16 After completing the deposition of the BCP layer, Ag (1 nm)/MoO_X (15 nm)was 17 thermally evaporated on top of BCP and the film was brought back to the nitrogen-18 filled glovebox, then completed the deposition of the SAM layer. For the narrow 19 band-gap PM6:BTP-eC9 system, the solution was prepared by dissolving blends with 20 a weight ratio of 1:1:0.2 in chloroform (total concentration 15.4 mg/mL) and stirred at 21 room temperature for 2 hours. The active layer was spin-coated on the ITO/SAM 1 substrates at 3500 rpm and then annealed 5 min at 80 °C. Finally, C60 (10 nm)/BCP

2 (5 nm)/Ag (100 nm) layers were deposited to complete the device fabrication.

3 2. Device performance characterization

The J-V characteristics were performed in N₂-filled glovebox under AM 1.5G (100 4 5 mW/cm²) by using a Keithley 2400 source meter unit and an AAA solar simulator 6 (SS-F5-3A, Enli Technology CO., Ltd.) calibrated by a standard Si photovoltaic cell. The external quantum efficiency (EQE) was measured by a certified incident photon 7 to electron conversion (IPCE) equipment (QE-R) from Enli Technology Co., Lt. The 8 light intensity at each wavelength was calibrated using a standard monocrystalline Si 9 10 photovoltaic cell. The bias illumination obtained by applying a 500 nm short-pass filter, and an 800 nm long-pass filter was used for the measurements of the bottom 11 subcell and the front subcell of perovskite-OPV TSC, respectively. 12

13 The analysis of J_{ph} vs V_{eff} relationships

14 The definition of J_{ph} is the current density under illumination (J_L) minus the dark 15 current density (J_D) , and V_0 refers to the voltage value when $J_{ph} = 0$. Accordingly, V_{eff} 16 = $V_0 - V_{appl}$, where V_{appl} represents applied voltage, has a clear meaning. Importantly, 17 when V_{eff} reaches a high value (> 2V) it is normally believed that generated excitons 18 are fully collected, in which J_{ph} is equal to saturated current density (J_{sal}) . Then, we 19 can calculate J_{SC}/J_{sat} and J_{max}/J_{sat} to describe exciton dissociation (η_{diss}) and charge 20 collection (η_{coll}) efficiency. J_{max} is the J_{ph} at the maximal output point.

21 Transient photovoltage (TPV) and transient photocurrent (TPC)

For TPV, the measurement was conducted under 1 sun conditions by illuminating the
 device with a white light-emitting diode, and the champion device is set to the open circuit condition. For TPC, the champion device is set to the short-circuit condition in
 dark. The output signal was collected by key sight oscilloscope.

5 Electrochemical analysis

6 Mott-Schottky characteristics and Nyquist plots were conducted using a PARSTAT 7 4000A electrochemical workstation, employing a three-electrode setup. For the curve 8 fitting of Mott-Schottky plots, the data were extracted by linear fitting the drop region 9 of Mott-Schottky plots, and V_{bi} was obtained via the intercept of the straight line with 10 the X axis.

11 Hole Mobility Measurements

12 The mobilities were measured by using a space charge limited current (SCLC) model 13 with the hole-only device of glass/ITO/SAMs/PM6: BTP-eC9/MoO3/Ag. Hole 14 mobility was obtained by fitting the current density-voltage curves and calculated by 15 the equation¹:

$$J(V) = \frac{9}{8} \varepsilon_0 \varepsilon_r \mu \frac{V^2}{L^2} \#(1)$$

17 Where *J* is current density, ε_0 is the permittivity of free space (8.85 × 10⁻¹⁴ F/cm), ε_r is 18 the relative permittivity of the material (assumed to 3), μ is hole mobility or electron 19 mobility, *V* is applied voltage and *L* is the thickness of film (~110 nm).

20 EQE_{EL} measurements

21 EQEEL measurements were done using a home-built setup using a Keithley 2400 to

inject current to the solar cells. Emission photon-flux from the solar cells was
 recorded using a Si detector (Hamamatsu s1337-1010BQ) and a Keithley 6482
 picoammeter.

4 Urbach energy (E_U)

5 E_U can be calculated from the slope of the straight line by plotting ln (α) against the

6 incident photon energy (E), which follows the straight-line equation below:

7
$$\ln \alpha(E) = \ln \alpha_0 + \frac{E}{E_u} - \frac{E_g}{E_u} \#(2) \#$$

8 3. Characterization of SAM

9 Instruments and characterization

10 Nuclear magnetic resonance (NMR) spectroscopy

11 1H NMR and 31P NMR spectra were recorded on Bruker (AVANCE III 400MHz).

12 X-ray photoelectron spectroscopy (XPS) was measured by Thermo Scientific K-

13 Alpha.

14 Contact angle measurements

15 The contact angles of water and formamide (FA) on SAMs coated ITO were

16 measured by a video optical contact angle meter (DSA-100 (KRUSS Germany)).

17 Then the surface free energy was calculated by Owens-Wendt method:^{2, 3}

18
$$\gamma_L \times (1 + \cos\theta) = 2 \times (\gamma_L^d \cdot \gamma_{sv}^d)^{\frac{1}{2}} + 2 \times (\gamma_L^p \cdot \gamma_{sv}^p)^{\frac{1}{2}} \#(3)$$

19 where γ_L and γ_{sv} are surface free energy of the probe liquid and sample, respectively.

20 The θ is the contact γ_L angle of the sample. The Flory-Huggins interaction parameter

1 $\chi_{donor-acceptor}$ for blends to show the binary miscibility was calculated from the 2 equation:

$$\chi_{door-acceptor} = K \left(\gamma_{donor}^{\frac{1}{2}} - \gamma_{donor}^{\frac{1}{2}} \right)^2 \#(4)$$

4 where γ is the surface energy of the material, *K* is the proportionality constant.

5 GIWAXS and XRD Measurement

6 GIWAXS measurements were performed at the Synchrotron & Printable Electronic
7 Lab, Hoffmann Institute of Advanced Materials, Shenzhen Polytechnic University
8 with SAXSFocus 3.0 (GKINST Co., LTD.) equipped with a Cu X-ray Source (8.05
9 keV, 1.54 Å) and an EIGER 2R 500K detector. The incident angle during the
10 measurement was maintained at 0.5° and the distance between sample and detector
11 was 132 mm.

12 For the GIWAXS and XRD measurement of SAM layers, the films were prepared by 13 spin-coating the control and TCB-treated SAM precursor solutions (2 mg/mL in IPA) 14 at 500 rpm for 30 s, followed by annealing at 130 °C for 5 min, the thicker films are 15 beneficial to obtain better signals.

16 Theoretical calculations

17 All the calculations of the model compounds studied in this work were performed 18 using the Gaussian 09 software package. Ground state geometry optimizations of 19 4PADCB, and TCB are calculated by DFT at the B3LYP/6-31G (d, p) (empirical 20 dispersion = gd3bj) level. The visualization of the molecular orbitals and ESP 21 distribution was performed using GaussView 6.0.16 and VMD software.⁴ The 1 reduced density gradient analysis was performed using MultiWfn3.8 software.^{5, 6}

2 **<u>4. Characterization of the active layer</u>**

3 Film-depth-dependent light absorption and composition distribution

4 Film-depth-dependent light absorption was carried out with an in-situ spectrometer
5 (PU100, Shaanxi Puguang Weishi Co. Ltd.) equipped with a soft plasma-ion source.
6 A 100 W power with an input pressure of ~10 Pa (oxygen) was used to generate soft
7 ionic source. The surface of the target film is gradually etched by the soft ion source,
8 without damage to the materials underneath. The absorption for the film during
9 etching was in-situ monitored by a spectrometer.

10 Atomic Force Microscopy (AFM) measurements

11 Topographic images of the films were obtained from a Bruker atomic force 12 microscopy (AFM) with the type of dimension edge with Scan Asyst in the tapping 13 mode using an etched silicon cantilever at a nominal load of \sim 2 nN, the scanning rate 14 for a 1 µm×1 µm image size was 0.9 Hz and 5 µm×5 µm image size was 1.0 Hz.

15 HAADF-TEM measurements

16 The films were floated off the substrates in deionized water and collected on lacey 17 carbon coated TEM grids (Electron Microscopy Sciences). HAADF-TEM were 18 performed on a Thermo Fischer Talos-200S TEM equipped with an electron 19 monochromator and a Gatan Imaging Filter (GIF) Quantum 966.

20 GIWAXS and GISAXS Measurement

21 The samples were fabricated by spin-coating the active layer precursor solutions onto

Si substrates. The incidence angles are 0.12° and the distances between sample and
 detector are 132 mm (GIWAXS) and 1000 mm (GISAXS) respectively. One
 dimensional experimental data were obtained with the SGTools software package
 programmed by Zhao et al.⁷

5 Data analysis.

6 The ordering degree of SAMs was quantified by using the Herman's orientation factor

7 (*f*), which is defined as follows:

$$f = \frac{1}{2} (3(\cos^2\theta) - 1) \# (5)$$

9 where the $\langle cos^2\theta \rangle$ is the average value of the square of the cosine of the azimuthal 10 angle for the scattering peak, which is calculated as follows:

$$\langle \cos^2 \theta \rangle = \frac{\int_{min}^{\pi/2} I(\theta) \cos^2(\theta) \sin(\theta) d\theta}{\int_{min}^{\pi/2} I(\theta) \sin(\theta) d\theta}$$
11

12 where $I(\theta)$ is the intensity at an azimuthal angle of θ .

13 The structural information of blend films such as the period of arrangement and 14 lamellar stacking spacing is obtained via the Bragg equation, as well as the crystal 15 coherence length (*CCL*) can be obtained from the Scherrer formula,⁸ and the specific 16 expressions of the Bragg equation and Scherrer formula are as follows:

$$d = \frac{\lambda}{2\sin(\theta)} = \frac{2\pi}{q} \#(7)$$

$$CCL = \frac{K\lambda}{FWHM \cdot \cos{(\theta)}} \#(8)$$

1 where d is the lamellar stacking spacing, and CCL is the crystal domain along the 2 specified direction called crystal coherence length, which is generally considered to 3 be equivalent to the grain size. λ is the value of X-ray wavelength; K is a 4 dimensionless shape factor,⁹ generally taken as K = 0.89; FWHM is the half-peak 5 width of the scattering peak; θ is the scattering angle.

6 GISAXS fitting model

7 To quantify and compare the phase separation, the IP (in plane) scattering profiles are 8 fitted with a model that describes the scattering contribution of each phase, the fitting 9 equation is shown in Eq. (1):

$$I(q) = \frac{A_1}{\left[1 + (q\xi)^2\right]^2} + A_2(P(q,R))S(q,R,\eta,D) + B\#(9)$$

11 where the first term was the so-called Debye-Anderson-Brumberger (DAB) term¹⁰, 12 modeling the scattering from the amorphous intermixing domains, and ξ is the 13 average correlation length of the amorphous domain.

14 The second term is the scattering intensity contribution from the small molecule pure domains in the co-monomer, where P(q, R) is the shape factor of the pure 15 16 domains. $S(q, R, \eta, D)$ is the structure factor of pure domains, and the fractal-like 17 network model is generally used to describe the cluster domains in the films 18 expressed as follows:

$$S(q) = 1 + \frac{\sin\left[(D-1)\tan^{-1}(q\eta)\right]}{(qR)^{D}} \cdot \frac{D\Gamma(D-1)}{\left[1 + \frac{1}{(q\eta)^{2}}\right]^{\frac{(D-1)}{2}}} \#(10)$$
19

20 where R is the mean radius, η is the coherence length of the fractal network, and D is 21 the fractal dimension of the structure. The average domain size can be estimated by 1 the Guinier radius of the fractal-like network Rg expressed as follows:



5 Fig. S1 TGA plots of TCB at a scan rate of 10°C min⁻¹ under inert atmosphere.



5 Table S1 The the overall average ESP values of DCB core and TCB, respectively.

	Overall average value (kcal/mol)
DCB Core	-1.11
TCB	2.33







9 (c)
$$q_{xy} \approx 9.5 \text{nm}^{-1}$$





9 ageing tests of thermal annealing



2 Fig. S9 (a) J-V dark curves of the device with the structure of ITO/control and TCB-



TCB Concentration (mg/mL)	<i>V_{oc}</i> (V)	J _{SC} (mA cm ⁻²)	FF	PCE (%)
0.1	0.860	28.38	79.63	19.44
0.3	0.862	28.57	79.41	19.54
0.5	0.863	28.83	80.64	20.06
0.8	0.863	28.57	79.74	19.67
1.0	0.863	28.45	79.69	19.57

5 Table S2 Detailed device parameters with varied concentration of TCB.

Temperature (°C)	<i>V_{oc}</i> (V)	J _{SC} (mA cm-2)	FF	PCE (%)
80	0.863	28.64	78.94	19.52
100	0.863	28.83	80.64	20.06
120	0.864	28.79	78.85	19.62

1 Table S3 Detailed device parameters with varied TA temperatures of SAM layer.

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2 Fig. S10 Certified Efficiency of PM6:BTP-eC9 binary OSCs device based on TCB-

3 treated SAM.

Active layers	Conditions	<i>V_{oc}</i> (V)	J _{SC} (mA cm ⁻²)	FF	PCE(Average) (%)
	Control	0.859	28.43	79.25	19.35
PM0:B1P-eC9	Target	0.863	28.83	80.64	20.06
	Control	0.910	26.68	78.91	19.16
PM6:L8-BO	Target	0.909	25.88	78.72	18.51
	Control	0.835	27.19	75.67	17.18
PM6: ¥ 6	Target	0.845	27.67	76.40	17.83
	Control	0.843	27.21	76.79	17.62
PM6:Y6:PC ₇₁ BM	Target	0.853	27.22	77.72	18.04

- 1 Table S4 Summary of the photovoltaic parameter of the device based on control and
- 2 TCB-treated SAM.



2 Fig. S11 Nyquist plots of devices based on control and TCB-treated SAM layer.





Fig. S13 FTPS-EQEs of the device based on control and TCB-treated SAM layer.



3 Fig. S14 Photographs of water and formamide droplets in contact with control and



9 Table S5 Surface energy (γ_s) of control and TCB-treated SAM layers.

ШТ	т	Contact		
HI	L	H ₂ O	FA	$\gamma_{\rm s}$ (min m ⁻¹)
SAI	М	50.87	36.23	49.47
SAM+	TCB	54.83	50.14	45.12



2 Fig. S15 The time evolutions of absorption peak of blend films during spin-coating.





Fig. S16 (a) GISAXS patterns and (b) scattering profiles of Yoneda peaks.

4 Table S6 Fitting data obtained from GISAXS patterns.

	Conditions	ζ (nm)	D	η (nm)	Rg (nm)
	Control	30.3	1.9	9.4	15.6
	TCB-treated	29.0	2.1	9.5	17.8
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2 Fig. S17 GIWAXS patterns and scattering profiles of active layer based on (a) control

- 3 and (b) TCB-treated SAM layer.
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- 6 Table S7 Detailed (010) peak information in the OOP direction of active layer based

7 on control and TCB-treated SAM layer.

Conditions	peak position (nm ⁻¹)	FWHM (nm ⁻¹)	<i>d-</i> spacing (nm)	CCL (nm)
Control	17.38	2.057	0.362	5.47
TCB-treated	17.45	2.001	0.360	5.62

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2 Fig. S18 AFM height images of active layer on (a) control and (b) TCB-treated SAM



- 8 Fig. S19 TEM images of active layer on on (a) control and (b) TCB-treated SAM
- 9 layer.
- 10



3 Fig. S20 (a) Film-depth-dependent absorption spectra, (b) exciton generation rate and

4 c) contours of active layer on control and TCB-treated SAM layers.

Band gap	<i>V_{oc}</i> (V)	J _{SC} (mA cm ⁻²)	FF	PCE (%)
1.85eV PSCs	1.300	15.97	82.98	17.24
1.36eV OSCs	0.858	28.90	79.68	19.75
Tandem	2.131	14.95	81.90	26.09

2 Table S8. The photovaltaic patameters of single junction and tandem devices.



8 Fig. S21 Statistical PCE versus FF of perovskite/organic solar cells in this work and

1 results reported in the literature.

$V_{oc}(\mathbf{V})$	<i>J_{SC}</i> (mA cm ⁻²)	FF (%)	PCE (%)	Ref.
1.96	13.3	80.3	20.9	11
2.05	13.4	76.8	21.0	12
1.88	15.7	74.6	22.0	13
2.06	14.8	77.2	23.6 (22.9 certified)	14
1.96	13.8	78.4	21.2	15
2.15	14.0	80.0	24.0 (23.1 certified)	16
2.10	13.1	75.1	20.6	17
1.94	13.1	78.7	20.0	18
2.22	12.7	76.0	21.4	19
2.07	13.9	77.3	22.3	20
2.15	13.4	80.3	23.2	21
2.07	13.9	76.9	22.4 (21.4 certified)	22
2.06	13.3	78.3	21.3	23
2.10	14.2	77.7	23.2	24
2.07	13.0	80.8	21.7	25
2.14	14.2	80.7	24.5	26
2.10	13.6	77.6	22.3	27
2.20	14.2	77.8	24.1	28
2.12	14.1	75.0	22.3	29
2.09	14.6	79.0	24.1	30

- 2 Table S9 Summary of photovoltaic performance of perovskite/organic solar cells in
- 3 the literature.

	2.06	12.7	77.4	20.2	31
	2.11	13.7	80.1	23.1	32
	2.15	14.4	81.7	25.2 (24.3 certified)	33
	2.12	14.7	83.0	25.8 (25.0 certified)	34
	2.16	15.4	79.4	26.4 (25.7 certified)	35
	2.13	14.6	82.8	25.9	36
	2.12	14.3	83.2	25.6 (24.7 certified)	37
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